

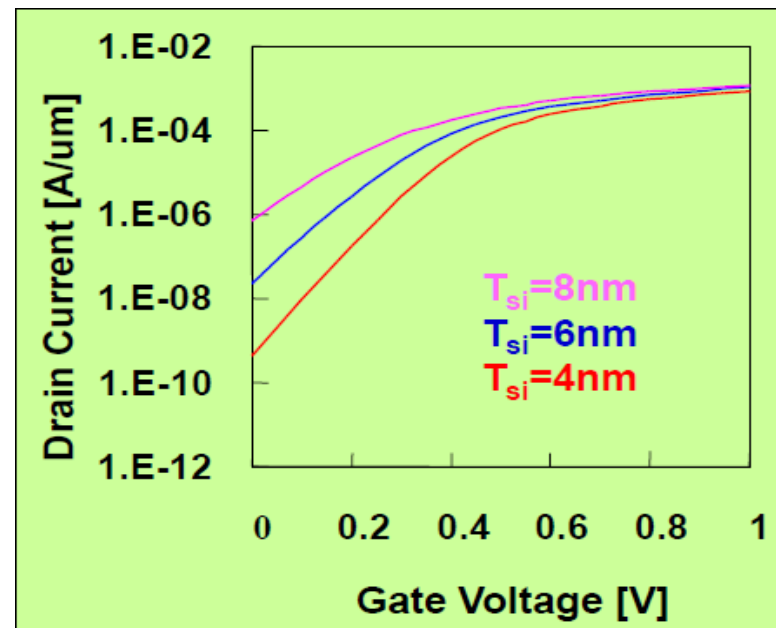
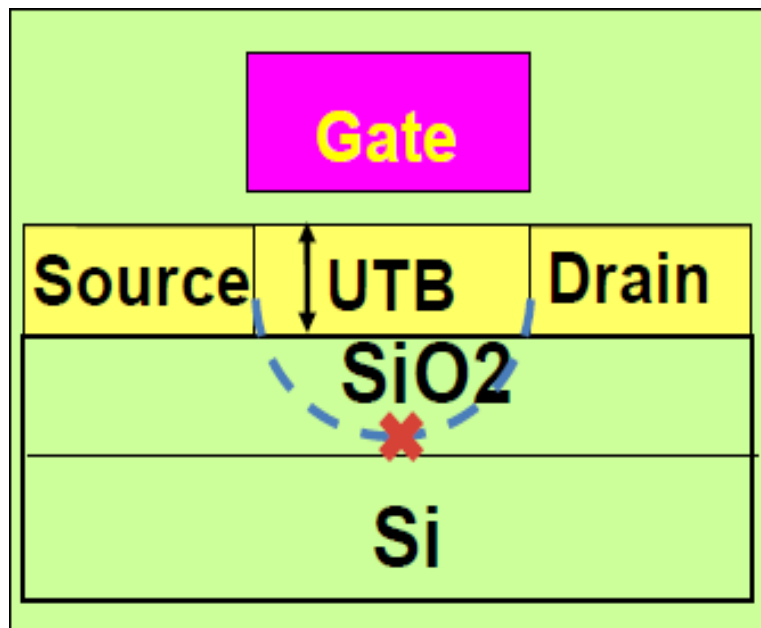
Recent Enhancements in BSIM-IMG

BSIM-IMG: Industry Standard Model with Fast and Extended Range Core Including Improved Mobility and Noise models

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Difficult to suppress leakage in Scaled MOSFET



- ❑ Need a thinner Oxide to suppress the leakage
- ❑ Gate Leakage is the Issue !

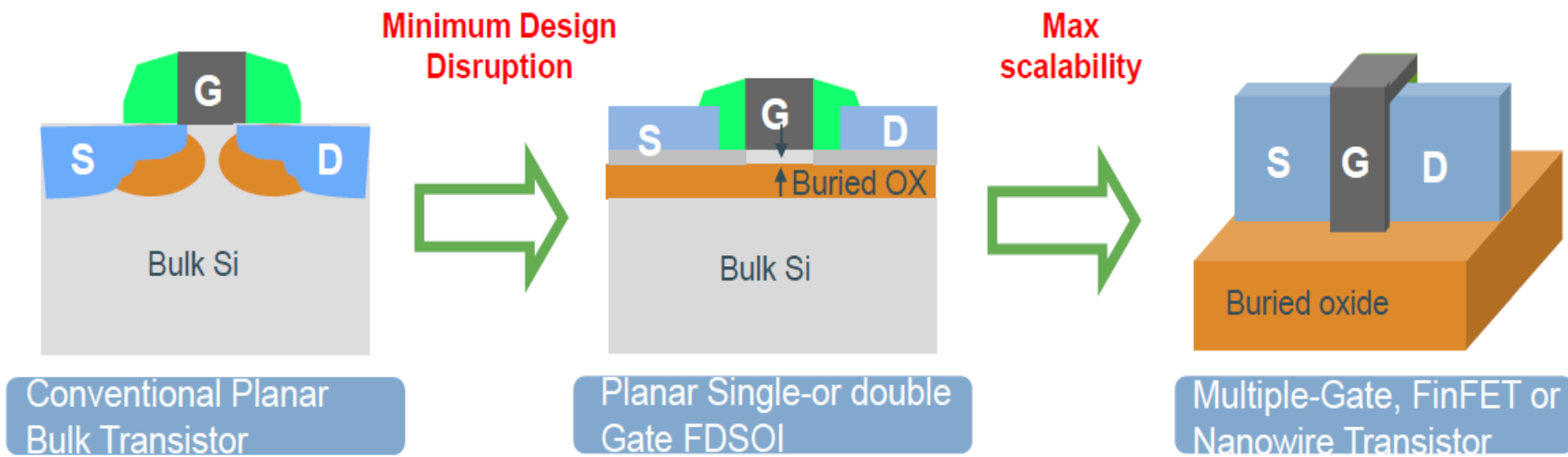
Solution:

Leakage is suppressed by multi-gates

Scale body thickness instead of Oxide thickness

Yang-Kyu Choi et.al, "Ultrathin-Body SOI MOSFET for Deep-Sub-Tenth Micron Era", IEEE electron device letters, vol. 21, no. 5, may 2000

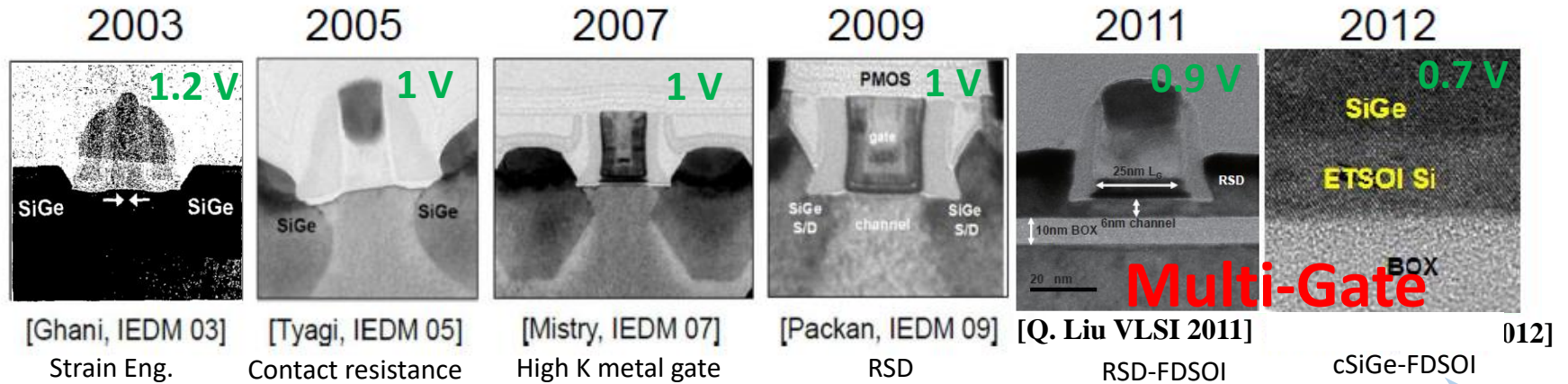
Examples of Multi-Gate



FDSOI : Fully Depleted Silicon-on Insulator

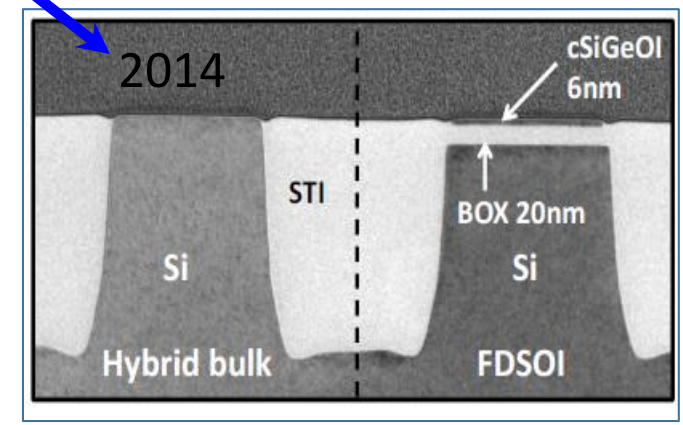
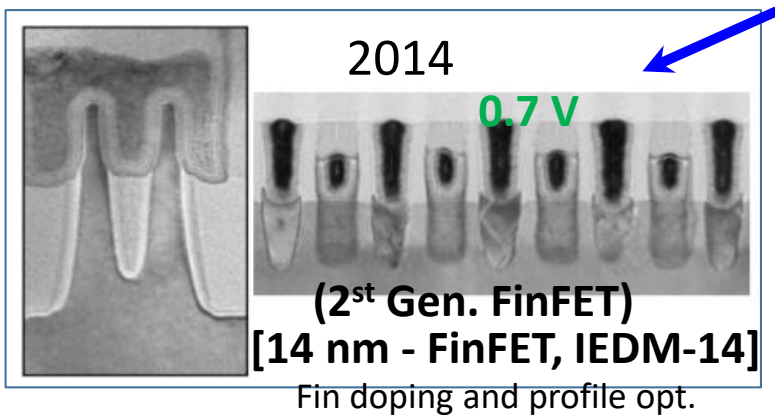
- Thin channel for (fully depleted) better gate control and Short channel effect (SCE)
- Better gate control \implies Better transistor scaling

Scaling: CMOS Solution



Multi-Gate

Multi-Gate



[14 nm - FDSOI, VLSI-TSA]

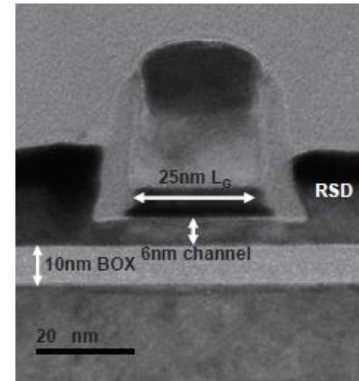
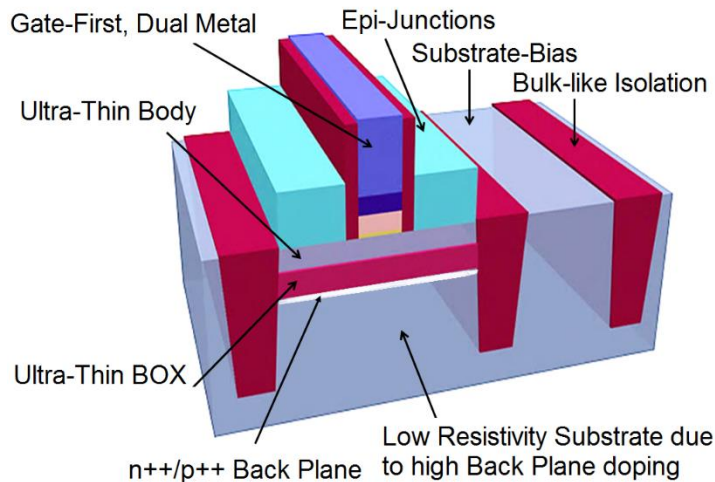
BSIM-IMG Developed for FDSOI Multi-gate MOSFET

Outline

- **BSIM-IMG: Independent Multi-gate MOSFET Model**
 - **Fast core Model**
 - **Extended Range Core Model**
- **Channel current, Charge and Capacitance Model**
- **Dual Mobility Model: g_m Double Hump Behavior**
- **Developed Noise Models in BSIM-IMG**

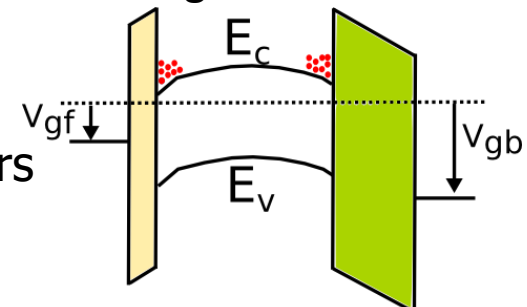
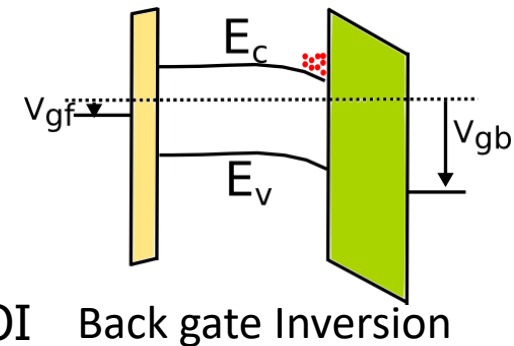
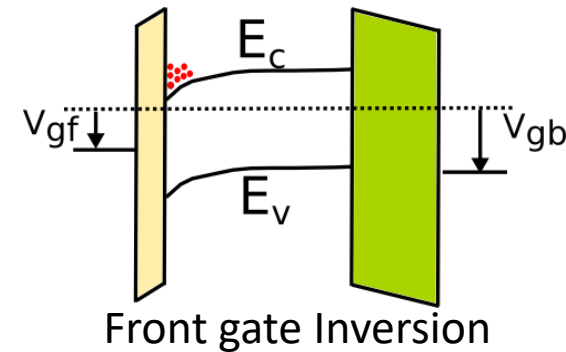
BSIM-IMG: Independent Multi-gate MOSFET Model

- Separate front and back gates
- Asymmetrical gate stack: T_{ox} , Work-function etc.



[Q. Liu VLSI 2011]

Target Device: UTBB SOI



Physical surface-potential-based core I-V and C-V model agrees with Numerical Solution without fitting parameters for surface potential

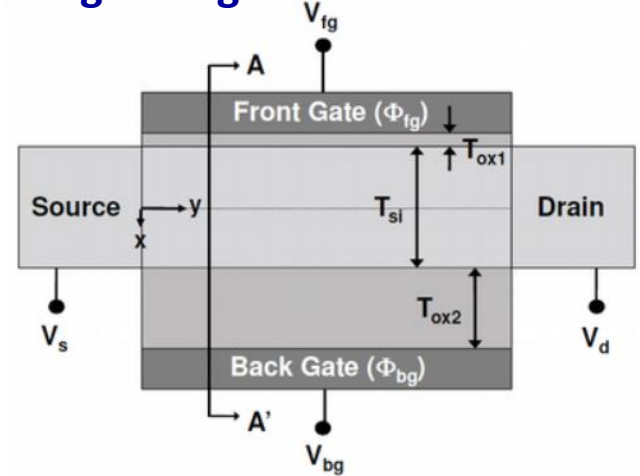
Fast Core Model

Solving Poisson's eq. in silicon body

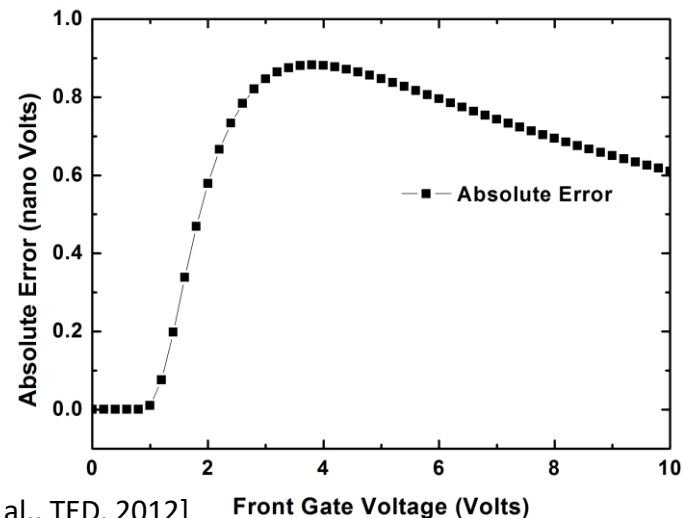
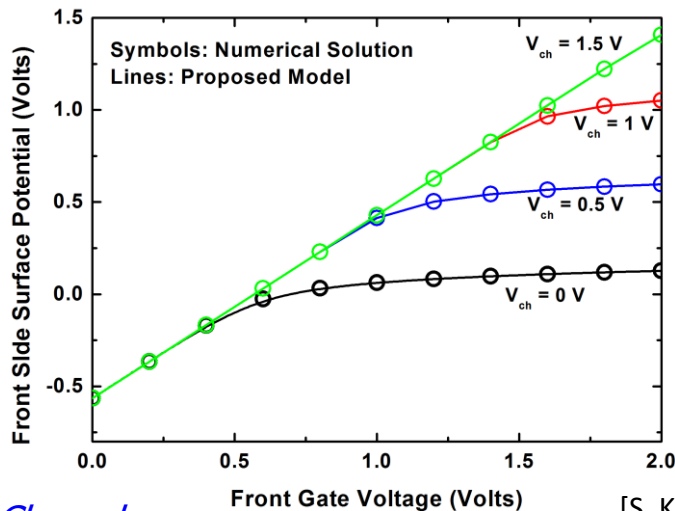
$$\left(C_{ox1} \frac{V_{fg} - \Delta\phi_1 - \psi_{s1}}{\epsilon_{Si}} \right)^2 - \left(C_{ox2} \frac{V_{bg} - \Delta\phi_2 - \psi_{s2}}{\epsilon_{Si}} \right)^2 = \frac{2qN_c V_{th}}{\epsilon_{Si}} \left[\exp \frac{\psi_{s1} - V_{ch}}{V_{th}} - \exp \frac{\psi_{s2} - V_{ch}}{V_{th}} \right] \dots(1)$$

$$\psi_{s2} = \frac{C_{Si}}{C_{Si} + C_{ox2}} \psi_{s1} + \frac{C_{ox2}}{C_{Si} + C_{ox2}} (V_{bg} - \Delta\phi_2) \dots(2)$$

Considering back gate in weak inversion



Solving (1) with proper initial guess, and using Helly's algorithm: Analytical Surface potential



Extended Range Core Model

Solving Poisson's eq. for undoped silicon body

$$\frac{\partial^2 \psi}{\partial x^2} = -\frac{\rho(\psi)}{\epsilon_{ch}} = \frac{qn_i}{\epsilon_{ch}} e^{\frac{\psi - V_{ch}}{v_T}} \dots (1)$$

Integrating Poisson's for front and back gate

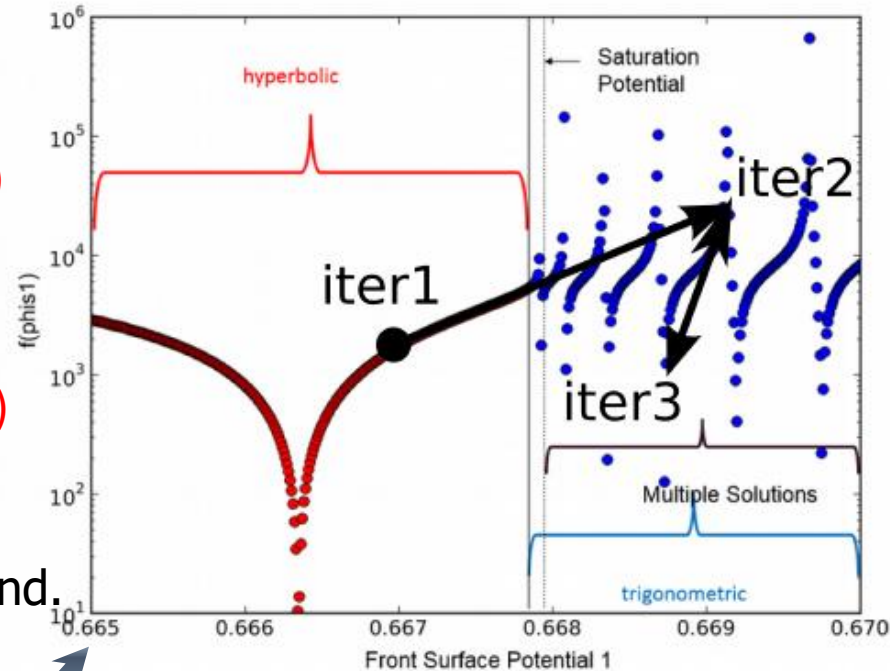
$$\left. \begin{aligned} \alpha^2 &= k_f(x_f - \varphi_f)^2 - A_0 e^{\varphi_f} \\ \alpha^2 &= k_b(x_b - \varphi_b)^2 - A_0 e^{\varphi_b} \end{aligned} \right\} \dots (2)$$

Integrating electric field and using boundary cond.

$$\alpha \coth(\alpha/2)(k_f(x_f - \varphi_f) + k_b(x_b - \varphi_b)) + k_f k_b(x_b - \varphi_b)(x_f - \varphi_f) + \alpha^2 = 0 \dots (3)$$

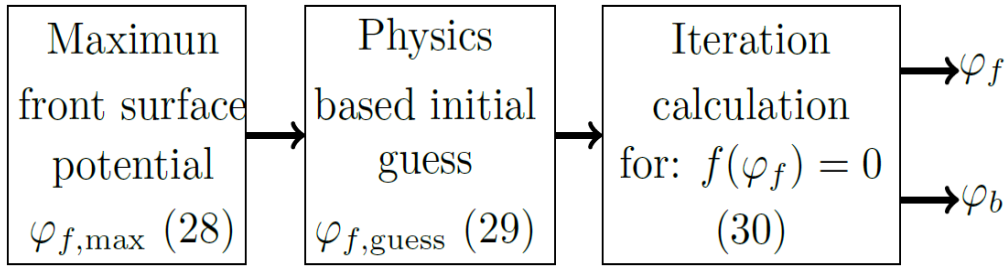
$$f(\varphi_f) = (k_f(x_f - \varphi_f) + \alpha \coth(\alpha/2))(k_f(x_f - \varphi_f) + k_b(x_b - \varphi_b)) - A_0 e^{\varphi_f} = 0$$

$$\varphi_b = \varphi_f - \ln(k_f(x_f - \varphi_f) + \alpha \coth(\alpha/2)) + \ln\left(\frac{\alpha}{\sinh(\alpha/2)}\right)^2 \dots (4)$$



Variable	Definition
x_f, x_b, v_T	$\frac{V_{GF} - \Delta\Phi_f}{v_T}, \frac{V_{GB} - \Delta\Phi_b}{v_T}, \frac{kT}{q}$ (thermal voltage)
φ_f, φ_b	$\frac{\phi_f}{v_T}, \frac{\phi_b}{v_T}$
$C_{ox,f}, C_{ox,b}, C_{ch}$	$\frac{\epsilon_{ox,f}}{EOT_f}, \frac{\epsilon_{ox,b}}{EOT_b}, \frac{\epsilon_{ch}}{T_g}$
$k_f, k_b, k_{eq,f}, k_{eq,b}$	$\frac{C_{ox,f}}{C_{ch}}, \frac{C_{ox,b}}{C_{ch}}, \frac{k_b}{k_f k_b + k_f + k_b}, \frac{k_f}{k_f k_b + k_f + k_b}$
A_0	$\frac{2qn_i \epsilon_{ch}}{C_{ch} v_T}$
q_m	$\frac{Q_m}{v_T C_{ch}}$

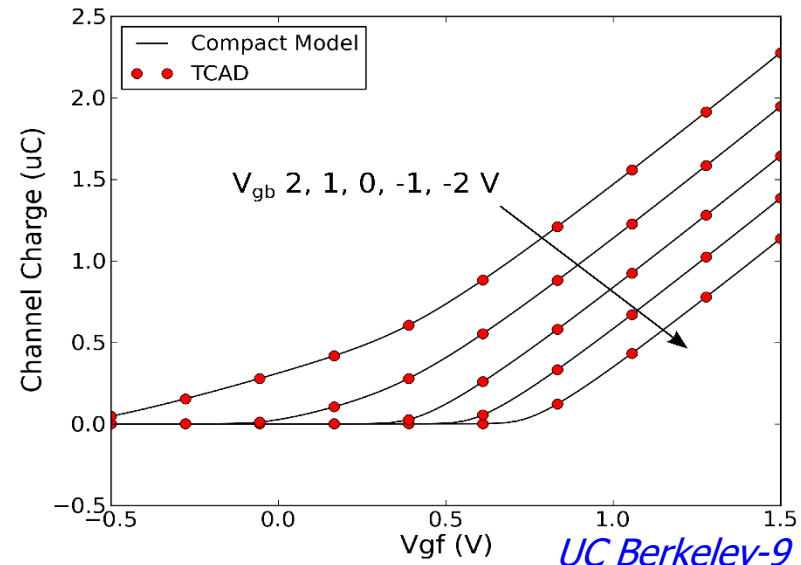
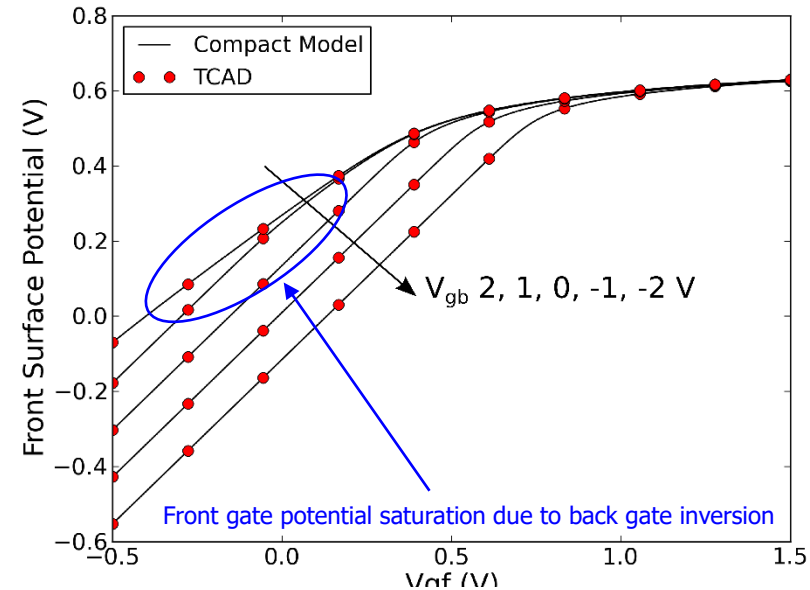
Extended Range Core Model: Analytical Solution



$$-4\pi^2 = k_f(x_f - \varphi_{f,\max})^2 - A_0 e^{\varphi_{f,\max}} \quad \dots (5)$$

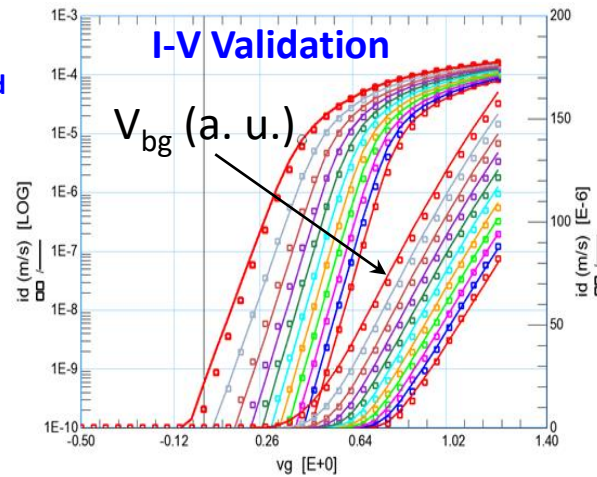
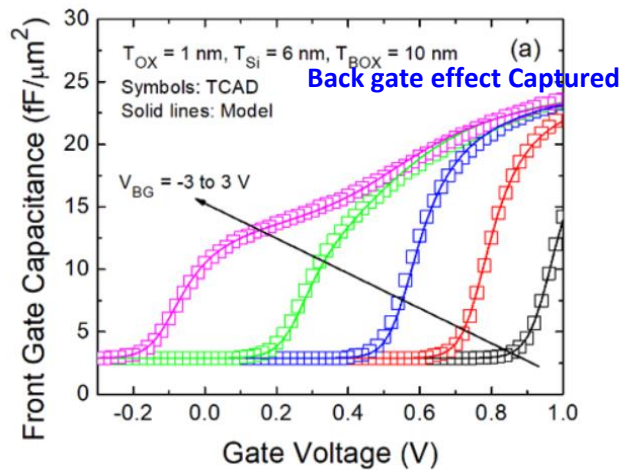
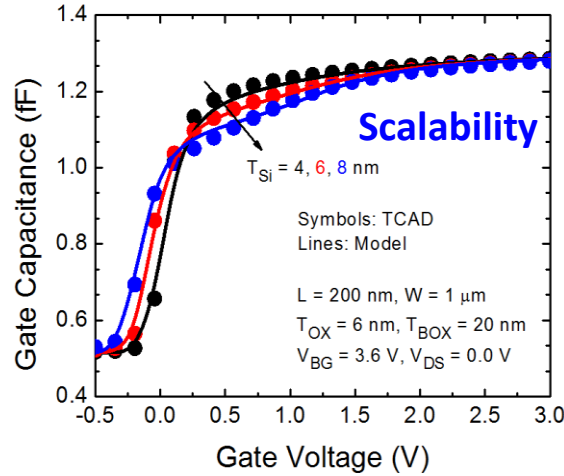
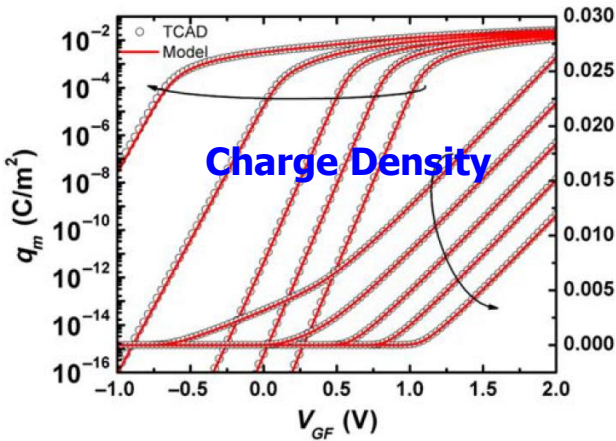
$$\varphi_{f,\text{guess}} = \max_s \left(\frac{rEOT_f(x_f - x_b)}{T_{fin} + r(EOT_f + EOT_b)} + x_b, \varphi_{f,\max} \right) \quad \dots (6)$$

Solving (6) and using proper initial guess in Newton raption algorithm:
Analytical Surface potential of (4) is obtained

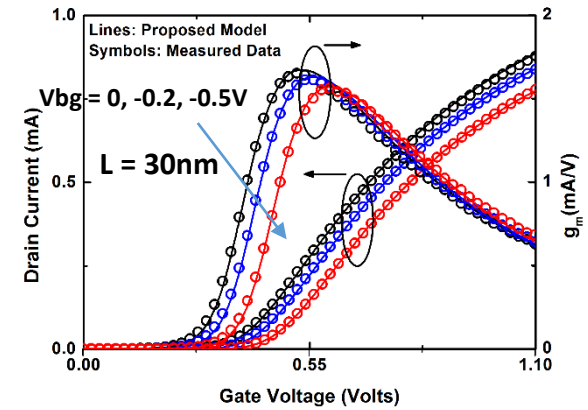


Channel current, Charge and Capacitance Model

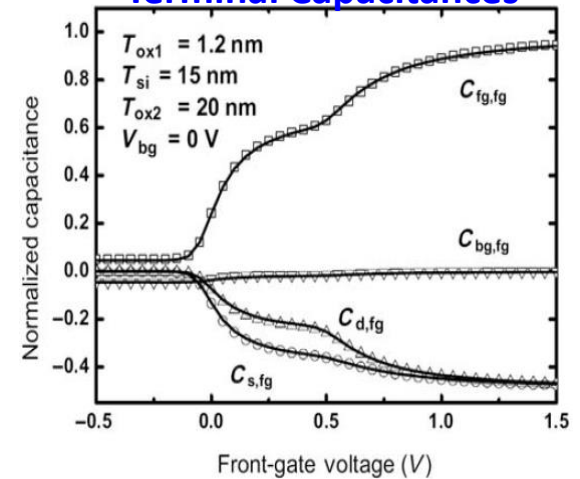
Extended Range Core Model



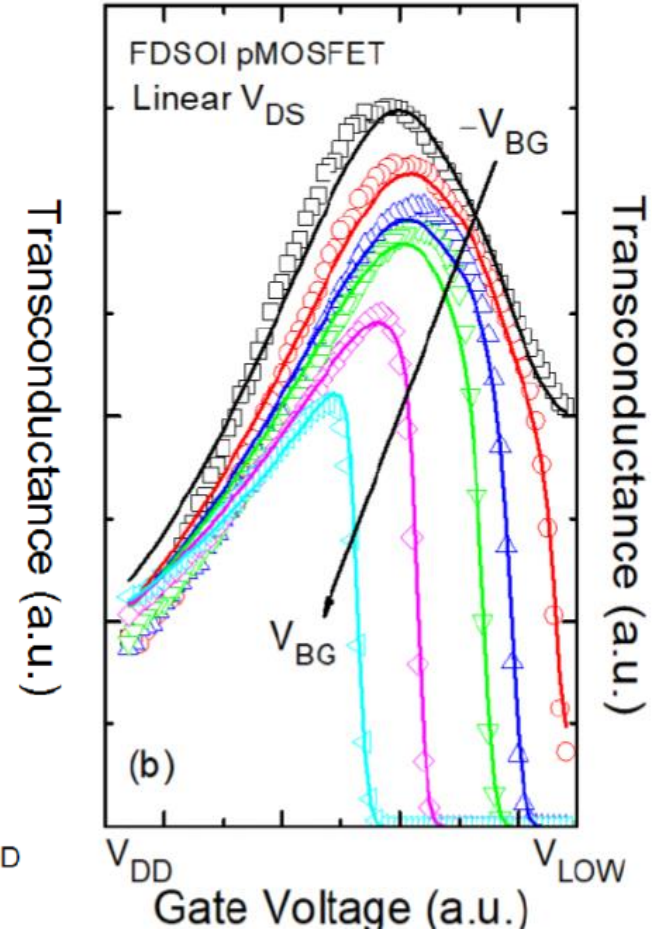
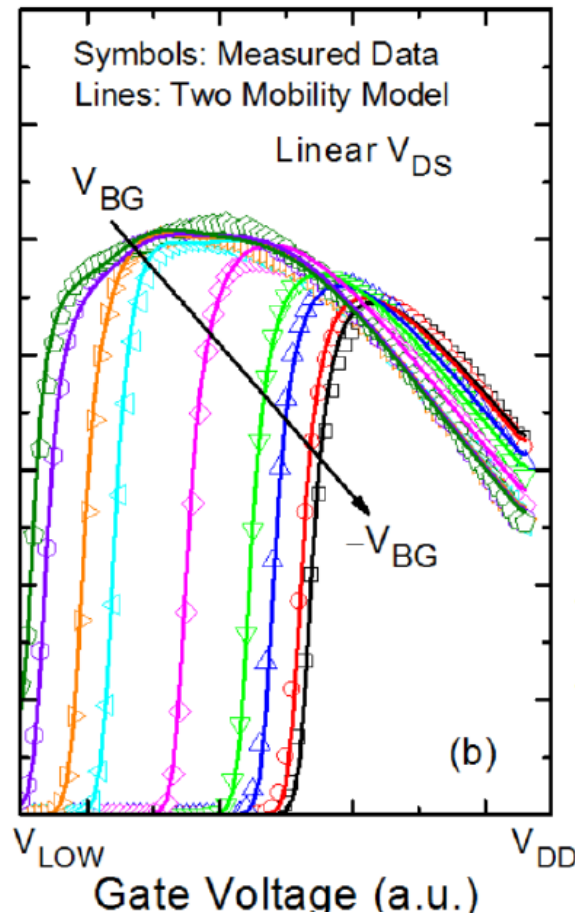
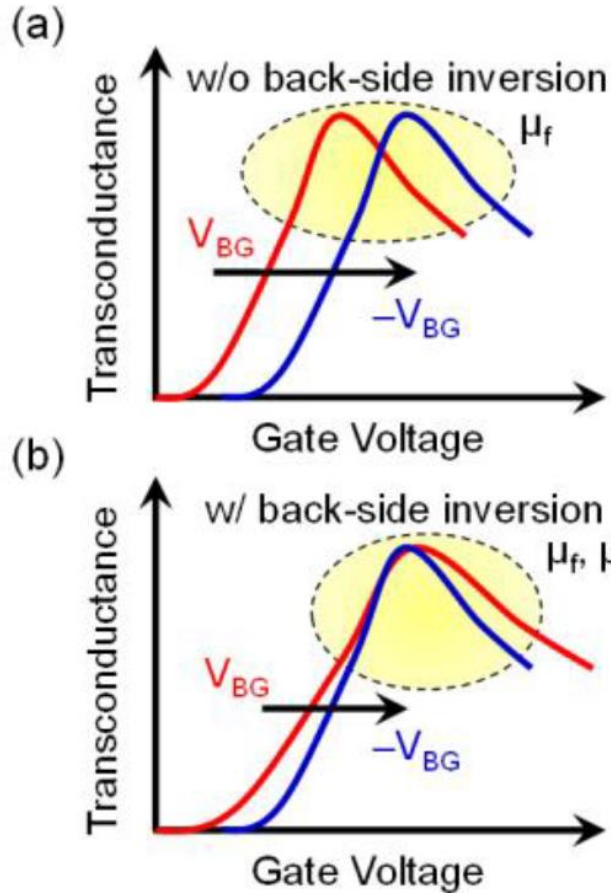
Fast Core Model I-V Validation



Terminal Capacitances



Dual Mobility Model: gm Double Hump Behavior



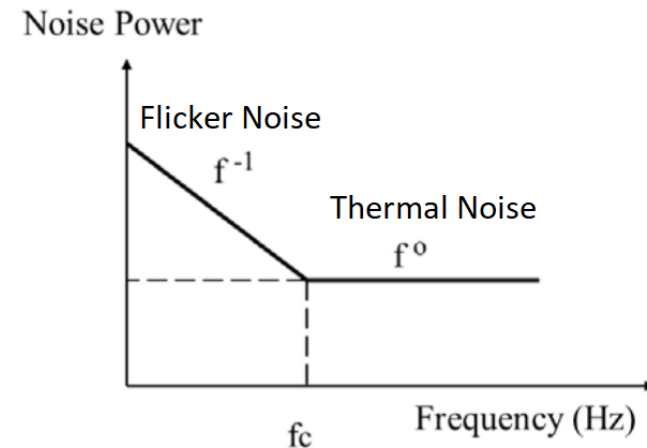
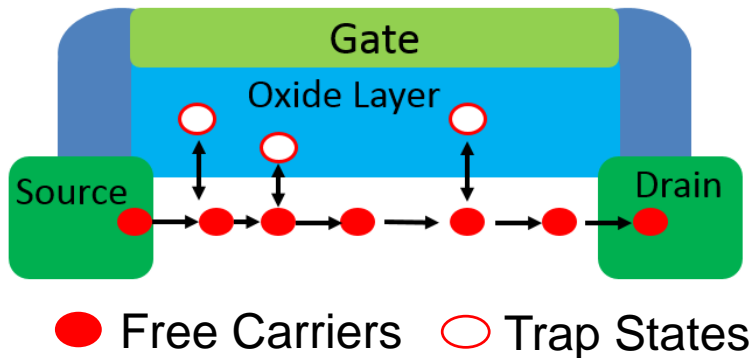
$$\mu_{t,eff} = w \cdot \mu_{eff,fg} + (1 - w) \cdot \mu_{eff,bg}$$

W is the weighting function

Thermal Noise Models in BSIM-IMG

❑ The major sources of noise in a transistor are the thermal noise and the flicker noise.

❑ Flicker Noise: Created by carrier trapping and de-trapping.



❑ Thermal Noise: Created by random motion of carriers due to thermal excitation.

Thermal Noise Models in BSIM-IMG

Earlier models only uses front gate for thermal noise PSD calculation

$$S_{id^2} = \frac{4K_B T}{I_D L_{vsat}^2} \int_0^{V_{DS}} g^2(V) \cdot dV \quad \text{KP equation}$$

Considering both front and back gate interface

$$g(V) = w C_{ox1} V_t (\mu_f q_f(v) + K \mu_b q_b(v))$$

Performing integration

$$S_{id^2} = \frac{4K_B T C_{ox1} V_t^3}{I_D L_{vsat}^2} (A_1 + B_1 + C_1)$$

$$A_1 = \mu_f^2 (q_{fs} - \beta q_{fd}) \left(\frac{q_{fs}^2 + q_{fs} q_{fd} + q_{fd}^2}{3} + \eta_f \frac{q_{fs} + q_{fd}}{2} \right)$$

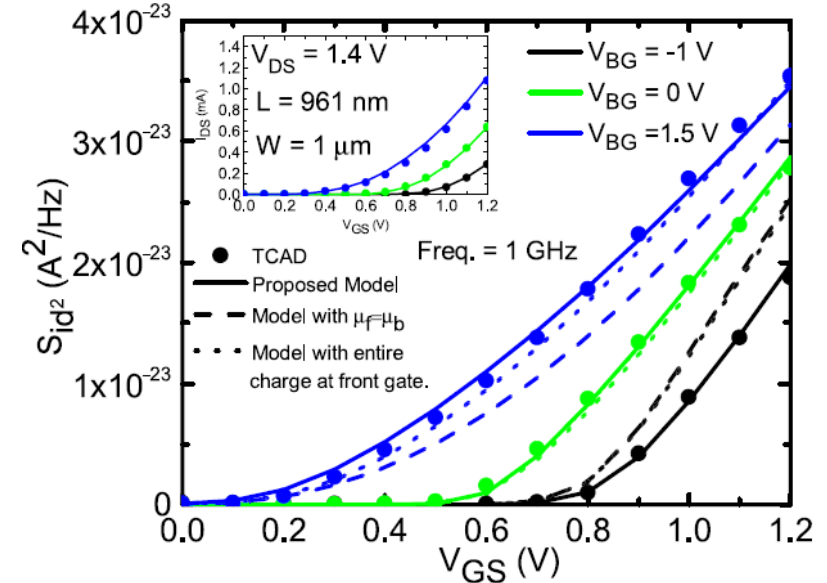
Front gate contribution

$$B_1 = K^2 \mu_b^2 (q_{bs} - \beta q_{bd}) \left(\frac{q_{bs}^2 + q_{bs} q_{bd} + q_{bd}^2}{3} + \eta_b \frac{q_{bs} + q_{bd}}{2} \right)$$

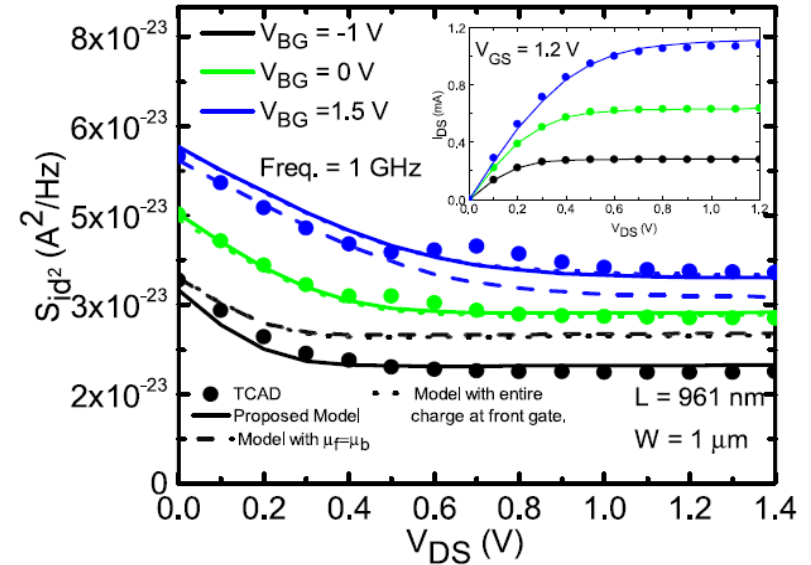
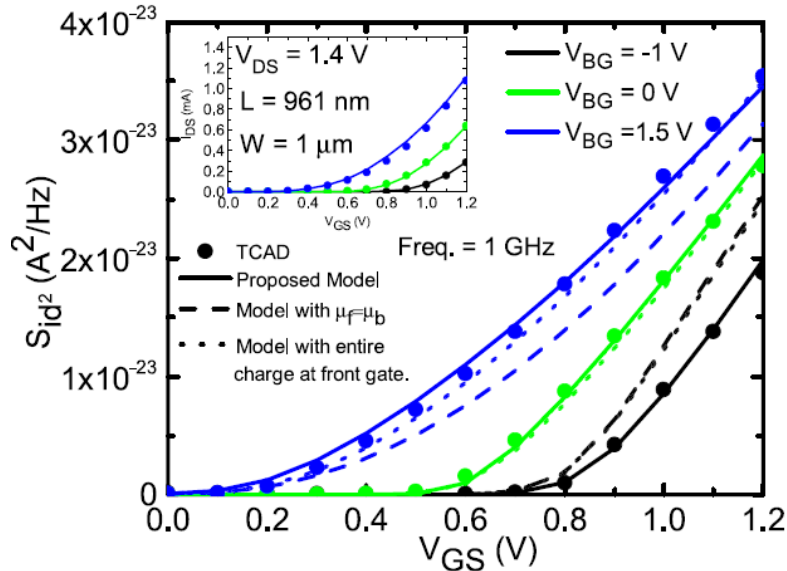
back gate contribution

$$C_1 = 2K \mu_f \mu_b q_{bav} (q_{fs} - \beta q_{fd}) \left(\frac{q_{fs} + q_{fd}}{2} + \eta_f \right)$$

coupling contribution



Thermal Noise Models in BSIM-IMG



More inversion charges as V_{gs} increases, more scattering, thermal noise

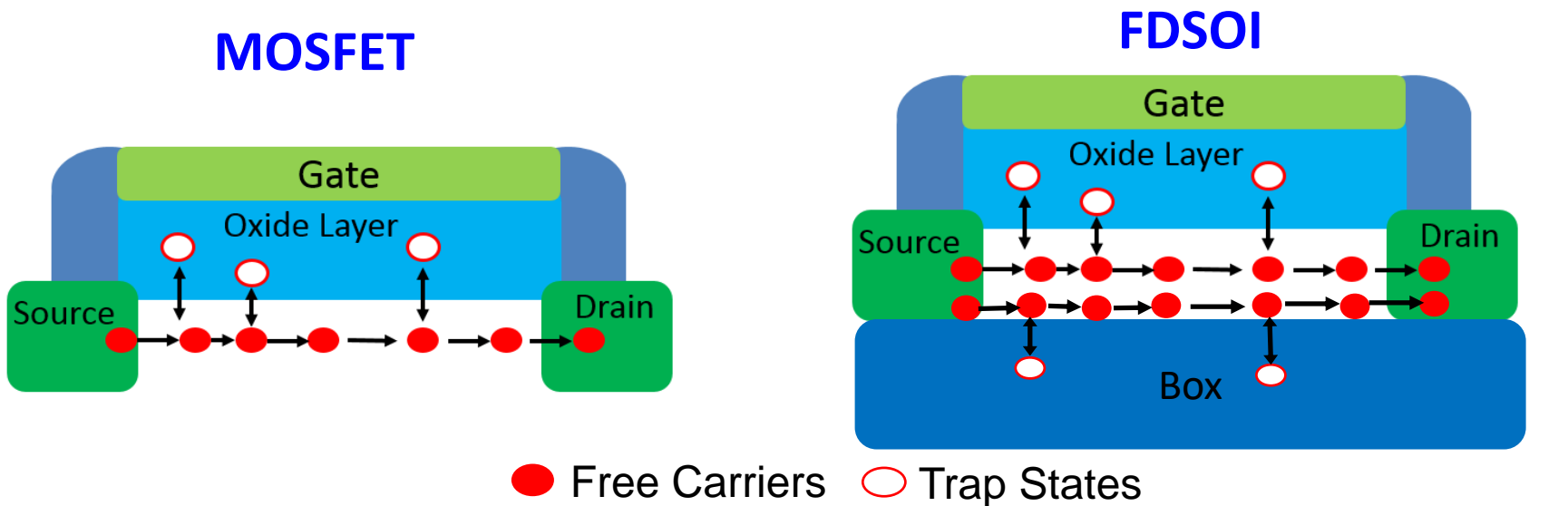
S_{id} is maximum @ $V_{ds} = 0$ V, starts to decrease as operating point move towards saturation (charge decreases)

- $+ V_{bg} \rightarrow V_t$ ↓ → more carriers → noise ↑
- $+ V_{bg} \rightarrow V_t$ ↑ → more carriers → noise ↓

- $+ V_{bg} \rightarrow V_t$ ↓ → more carriers → noise ↑
- $+ V_{bg} \rightarrow V_t$ ↑ → more carriers → noise ↓

Flicker noise – FDSOI MOSFET Models

FDSOI transistor faces more carrier fluctuations due to the presence of the front and back interfaces (carrier trapping and de-trapping)



- Single Si-SiO₂ interface
- Scaling issues

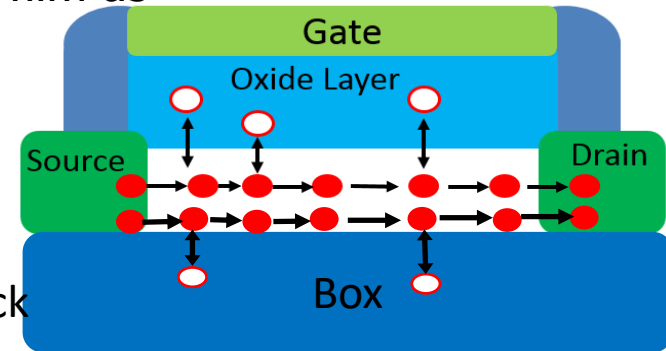
- Dual Si-SiO₂ interface
- Good Scaling solution

Flicker noise – BSIM-IMG Model

The charge fluctuations near both interfaces contribute to total inversion charge fluctuation (dQ_{inv}) in thin silicon film as

$$dQ_{inv} = \underbrace{\frac{\partial Q_{inv}}{\partial N'_{t1}} dN'_{t1}}_{\text{Front Interface}} + \underbrace{\frac{\partial Q_{inv}}{\partial N'_{t2}} dN'_{t2}}_{\text{Back Interface}}$$

----- (1)



Fluctuation in the amount of trapped oxide charges at front/back interfaces will cause

Correlated fluctuation in effective mobility
Correlated fluctuation in carrier number

ultimately
fluctuates
the current

$$\frac{dI_{ds}}{I_{ds}} = dN'_{t1} \left[\underbrace{\frac{1}{N'_{t1}} \frac{\partial N'}{\partial N'_{t1}}}_{R_{front}} + \underbrace{\frac{1}{\mu_{eff}} \frac{\partial \mu_{eff}}{\partial N'_{t1}}}_{\mu_{N_{t1}} * \alpha_1} \right] + dN'_{t2} \left[\underbrace{\frac{1}{N'_{t2}} \frac{\partial N'}{\partial N'_{t2}}}_{R_{back}} + \underbrace{\frac{1}{\mu_{eff}} \frac{\partial \mu_{eff}}{\partial N'_{t2}}}_{\mu_{N_{t2}} * \alpha_2} \right]$$

----- (2)

$$R_{back} = \frac{\delta \Delta N}{\delta \Delta N_{t2}} = \frac{\partial Q_{inv_{norm}}}{\partial V_{bg}} = C_{ox1} \left(\frac{\partial V_{fg,eff}}{\partial V_{bg}} - \frac{\partial \psi_{s1}}{\partial V_{bg}} \right) + \frac{C_{si} \cdot C_{ox2}}{C_{si} + C_{ox2}} \left(1 - \frac{\partial \psi_{s1}}{\partial V_{bg}} \right)$$

$$R_{front} = \frac{\delta \Delta N}{\delta \Delta N_{t1}} = \frac{\partial Q_{inv_{norm}}}{\partial V_{fg}} = -\frac{1}{C_{box}} \frac{N}{N + N_1^*}; N_1^* = \frac{KT}{q^2} (C_{ox} + C_{it})$$

Flicker noise – BSIM-IMG Model

From the number fluctuation theory and following assumptions

- Oxide trap have a uniform distribution near the interface
- Tunneling probability decreases exponentially in vertical direction

$$S_{\Delta I_{ds}}(x, f) = \left(\frac{I_{ds}}{W \cdot \Delta x} \right)^2 \left(\frac{R_{front}}{N} \pm \alpha_1 \mu_{eff} \right)^2 S_{\Delta N_{t1}}(x, f) + \left(\frac{I_{ds}}{W \cdot \Delta x} \right)^2 \left(\frac{R_{back}}{N} \pm \alpha_2 \mu_{eff} \right)^2 S_{\Delta N_{t2}}(x, f) \quad (3)$$

$$S_{\Delta N_{t1/t2}}(x, f) = N_{t1/t2}(x, f) \left(\frac{kT \cdot W \cdot \Delta x}{\gamma \cdot f} \right)$$

PSD of local current fluctuation

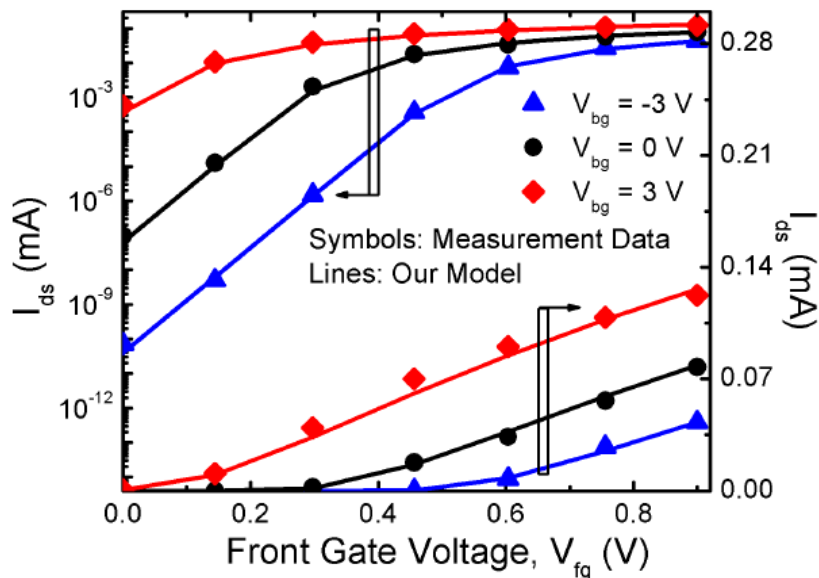
PSD of mean square fluctuation

Total drain current noise PSD

$$S_{I_{ds}}(f) = \frac{1}{L^2} \int_0^L S_{\Delta I_{ds}}(x, f) \cdot \Delta x \cdot dx = \frac{kT \cdot q \cdot I_{ds} \cdot \mu_{eff}}{\gamma \cdot f \cdot L^2} \int_0^{V_{ds}} \left[N_{t1}^*(E_{fn}) \frac{R_{front}^2}{N} + N_{t2}^*(E_{fn}) \frac{R_{back}^2}{N} \right] dV \quad (4)$$

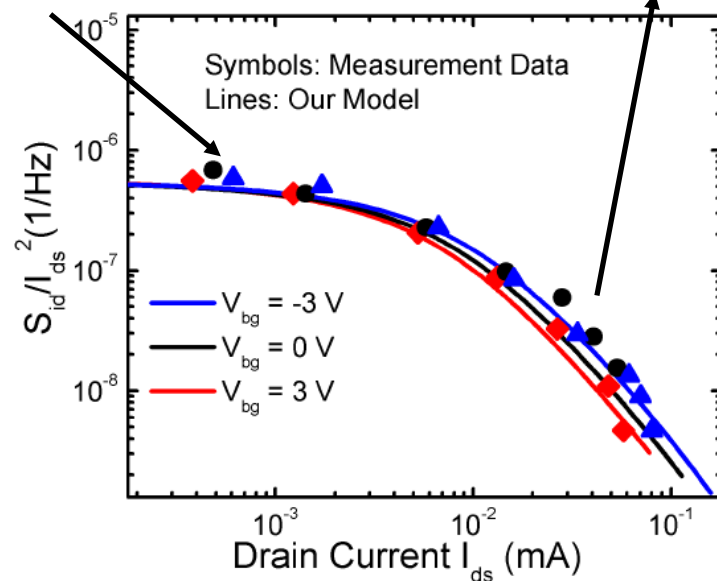
$N_{t1/t2}^*(E_{fn}) =$ Trap distribution around quasi Fermi level – Delta function
 MOS-AK, Chengdu

Flicker noise – BSIM-IMG Model

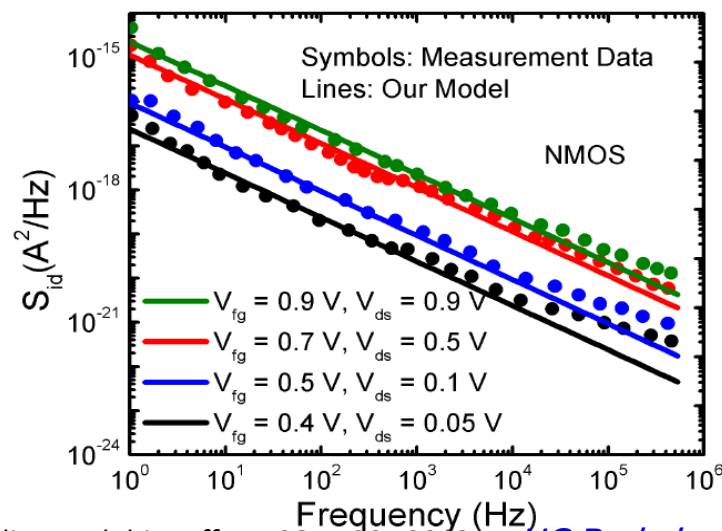


Negligible effect of back-bias (CNF)

Mobility fluctuates With back-bias (CMF)



- The threshold voltage shift due to different back gate biases is captured very well.
- Model is following CNF model in weak inversion region.
- Model is following CMF model in strong inversion region.
- Model shows correct trends (1/f –like spectra) for all drain biases which implies model's robustness from linear to saturation region.



Gate induced noise – BSIM-IMG Model

Channel charge fluctuation cause a redistribution of the channel potential which results in a charge redistribution across the gate capacitor. This fluctuation is capacitively coupled to the gate charge at the RF frequency, and result in a noise current (rate of change of charge) at the gate terminal.

KP equation

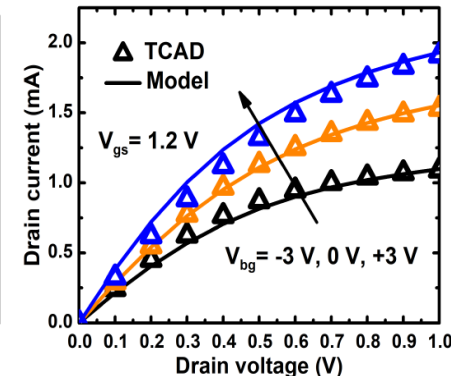
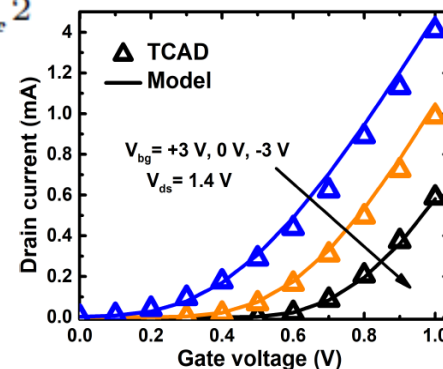
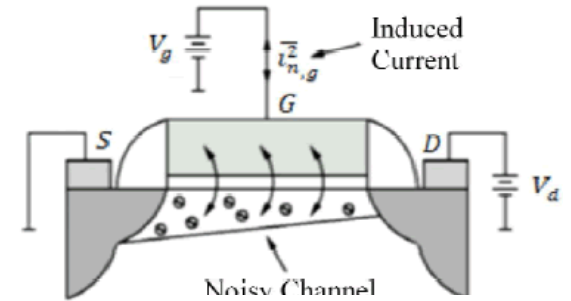
$$S_{ig^2} = P_{S_{ig^2}} \int_{V_s}^{V_d} g_0^2(v) \left[\int_{V_s}^{V_d} (Q(u) - Q(v)) g_0(u) du \right]^2 dv$$

$$S_{ig,id} = P_{S_{ig,id}} \int_{V_s}^{V_d} g_0^2(v) \int_{V_s}^{V_d} g_0(u) (Q(u) - Q(v)) dudv$$

$$P_{S_{ig^2}} = \frac{16\pi^2 kT f^2 W^2}{I_{ds}^5 L_{eff}^2} \quad P_{S_{ig,id}} = \frac{-j8\pi kT f W}{I_{ds}^3 L_{eff}^2}$$

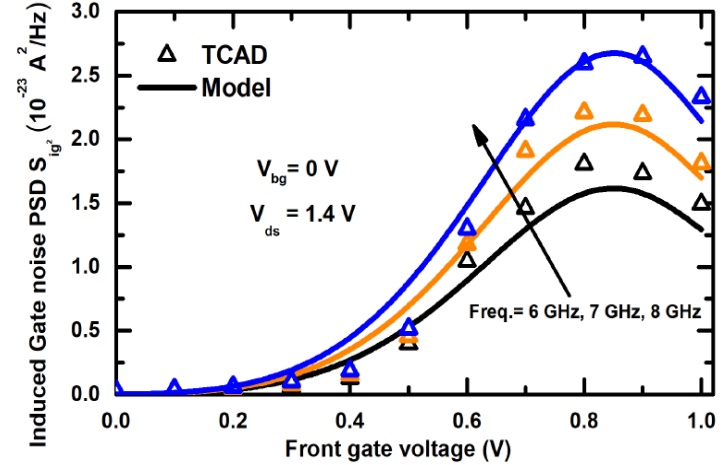
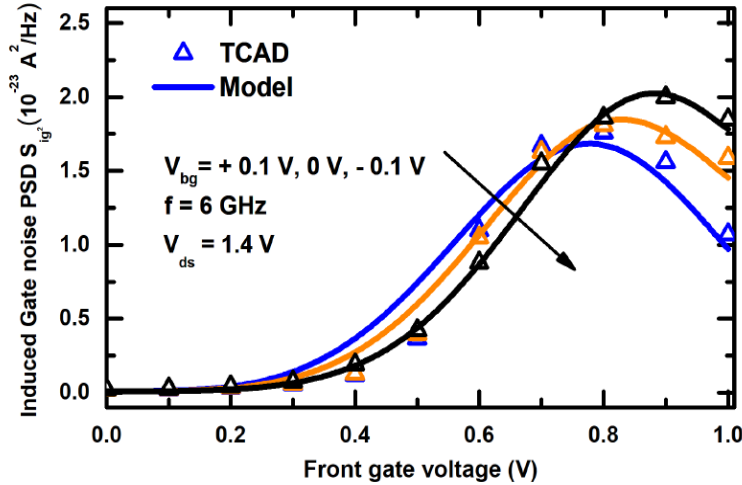
$$Q = C_{ox1} V_t (q_f + K q_b)$$

$$Q_{f(b)N} = \frac{q_{f(b)s}^N - q_{f(b)d}^N}{N} + \eta_{f(b)} \frac{q_{f(b)s}^{N-1} - q_{f(b)d}^{N-1}}{N-1}$$



C. K. Dabhi et. al. "Modeling of Induced Gate Thermal Noise Including Back-Bias Effect in FDSOI MOSFET," in *IEEE MWCL*, vol. 28, July 2018.

Gate induced noise – BSIM-IMG Model



- Increase in semiconductor charge with increasing front gate voltage results in more scattering due to increase in the field and hence more noise.
- Increasing the back gate bias also leads to an increase in the total semiconductor charge, resulting in higher noise for higher back gate bias.

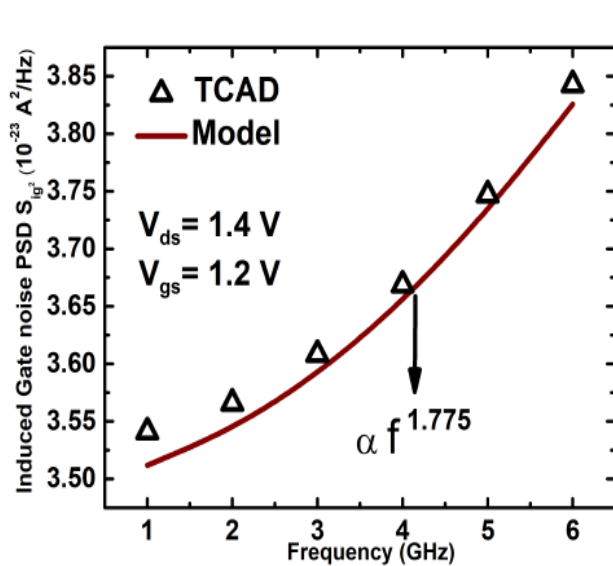
$$S_{ig^2} = \frac{16\pi^2 q f^\theta L_{vsat}^3}{WC_{ox}^3 V_t^9 m_{id}^5} (T_I - U_I + X_I); S_{ig,id} = \frac{-j8\pi q f L_{vsat}}{C_{ox} V_t^3 m_{id}^3} \left(\frac{2T_I - U_I}{2P_I} \right)$$

$$T_I = P_I^2 (\mu_f^2 Q_{f3} + 2\mu_f \mu_b q_{av} Q_{f2} + \mu_b^2 Q_{b3}); P_I = WC_{ox}^2 V_t^3 [\mu_f Q_{f3} + K^2 \mu_b Q_{b3} + K q_{av} (\mu_f + \mu_b) Q_{f2}]$$

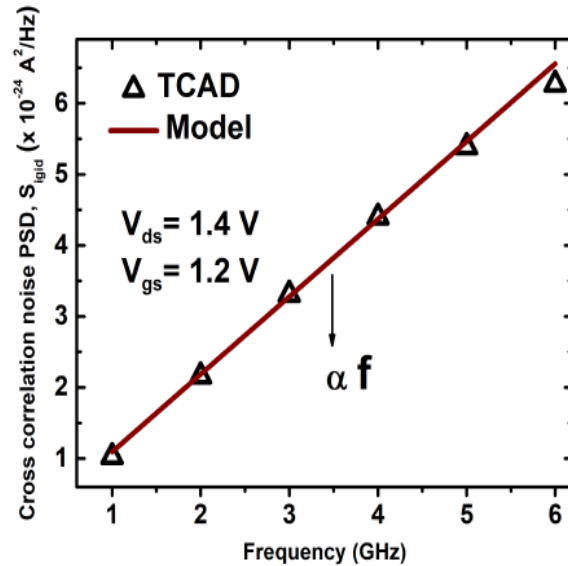
$$U_I = 2P_I WC_{ox}^2 V_t^3 (\mu_f Q_{f2} + \mu_b K Q_{b2}) [\mu_f^2 Q_{f4} + (\mu_f q_{av} Q_{f3}) (\mu_f K + 2\mu_b) + (\mu_b q_{av}^2 Q_{f2}) (2\mu_f K + \mu_b) + \mu_b^2 K q_{av}^3 Q_{f1} + \eta_f (\log(q_{fs}) - \log(q_{fd}))]$$

$$X_I = [WC_{ox}^2 V_t^3 (\mu_f Q_{f2} + \mu_b K Q_{b2})]^2 [\mu_f^2 Q_{f5} + 2q_{av} \mu_f Q_{f4} (\mu_b + \mu_f K) + q_{av}^2 Q_{f3} (\mu_b^2 + 4\mu_f K \mu_b + K^2 \mu_f^2) + 2\mu_f \mu_b K^2 q_{av} Q_{f2} (1 + q_{av})]$$

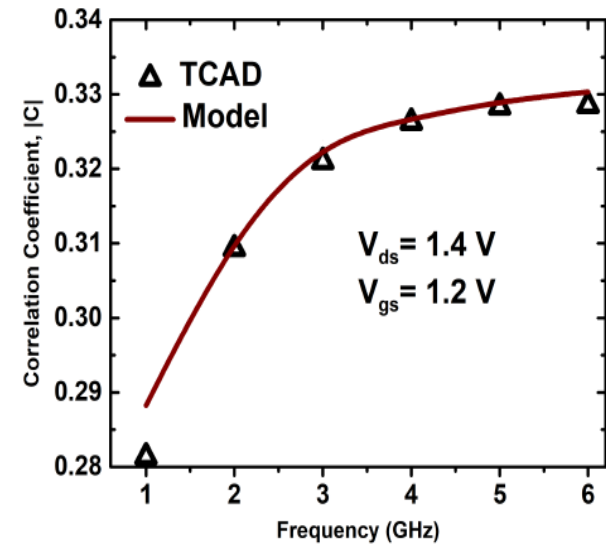
Gate induced noise – BSIM-IMG Model



(a)



(b)

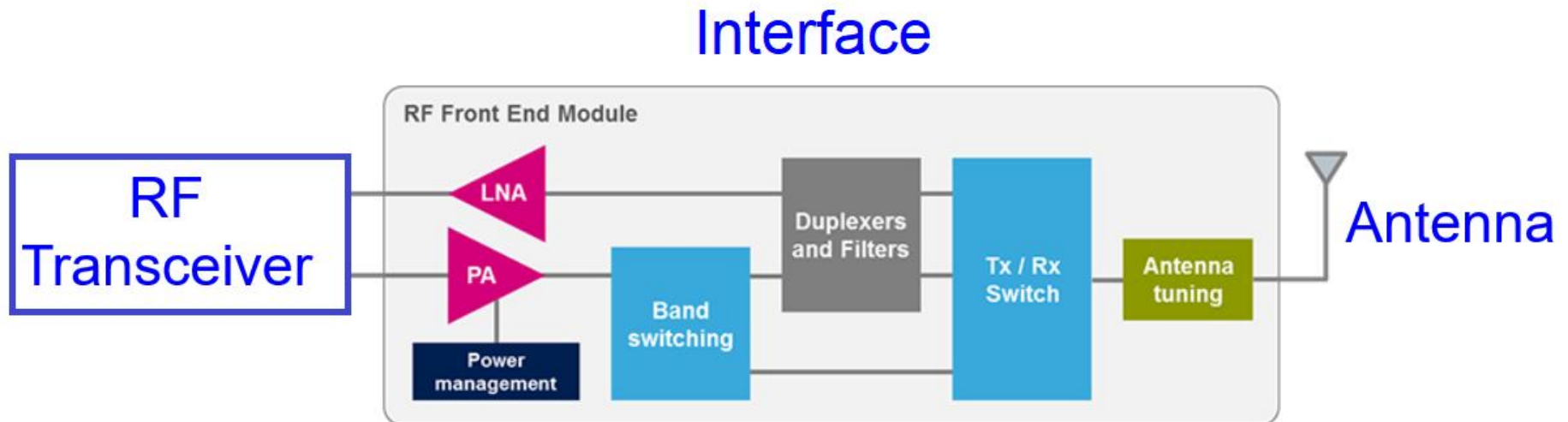


(c)

- As the frequency increases, the impedance of the effective capacitance coupling between the gate and the channel brings in a frequency dependence
- Increase in cross-correlation PSD at higher frequency due to capacitive coupling

Requirement of RF Modeling of FDSOI MOSFETs

- In cellular and Wi-Fi systems, the Radio Frequency (RF) Front-End Module is one of the most critical parts.

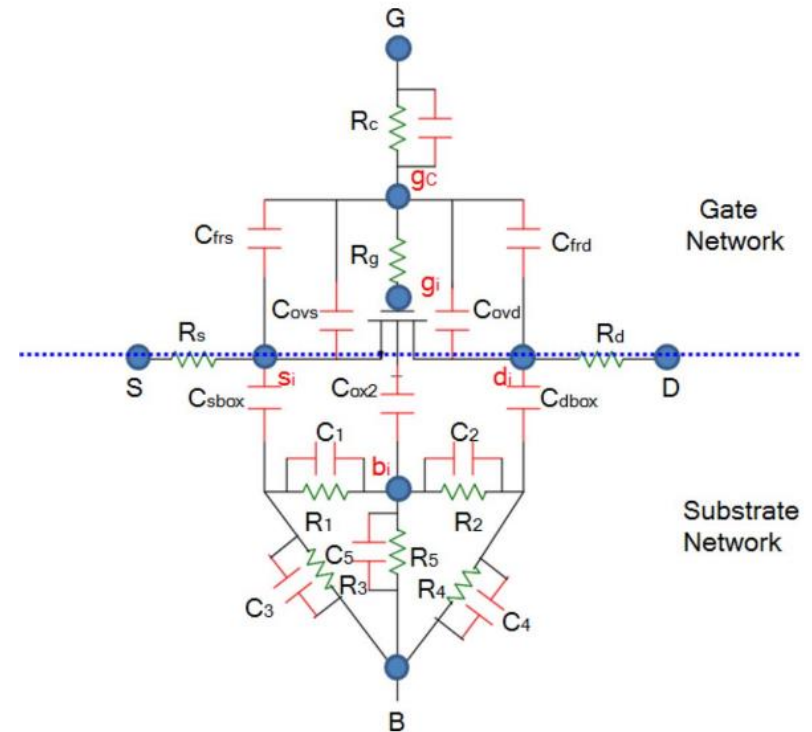


Requirement \Rightarrow RF circuits

High performance system on chip (SOC), which includes mix signal, complex high power devices, trans-receiver, high resistivity (HR) silicon SOI substrates (RFSOI substrate) make it possible

RF Modeling of FDSOI MOSFETs

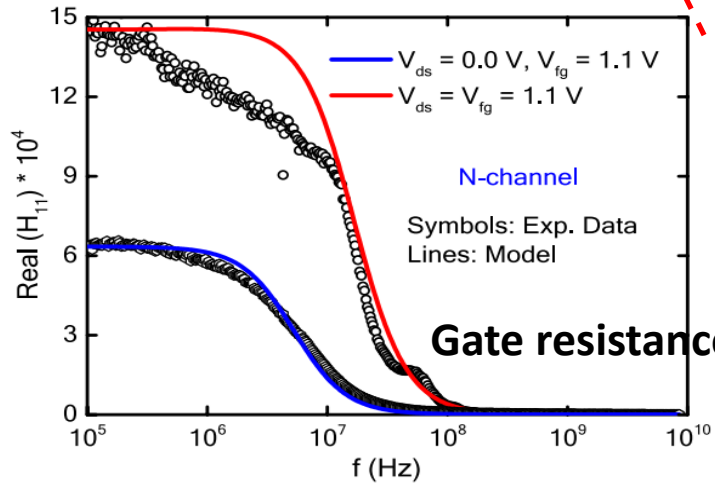
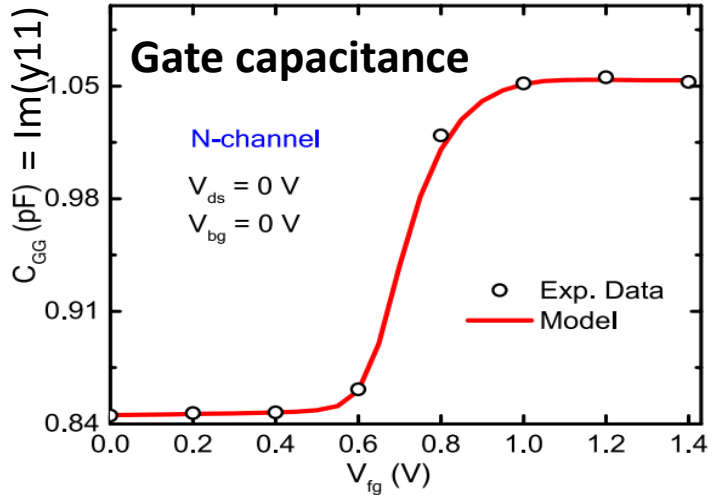
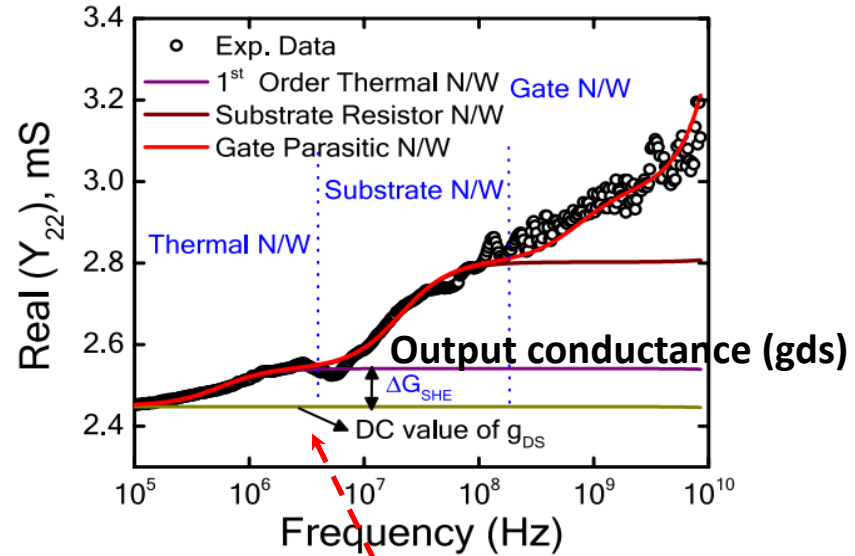
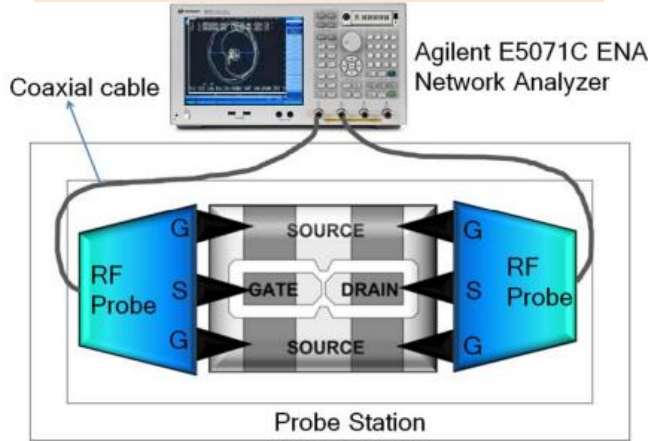
- In MOS devices the effect of parasitic resistances and capacitances showed up at higher frequency.
- When MOSFET is operated in gigahertz range, the extrinsic part of the transistor is of more concern than its intrinsic part.
- The accurate modeling of the following are highly important.
 - 1: Gate electrode resistance.
 - 2: Source/Drain series resistance.
 - 3: Parasitic capacitance.
 - 4: Substrate resistance.



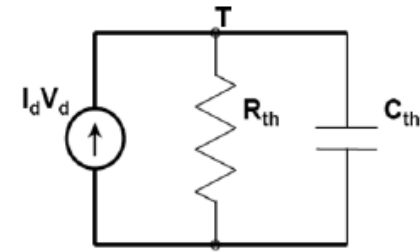
RF Modeling of FDSOI MOSFETs

Parameter extraction for DC characteristics

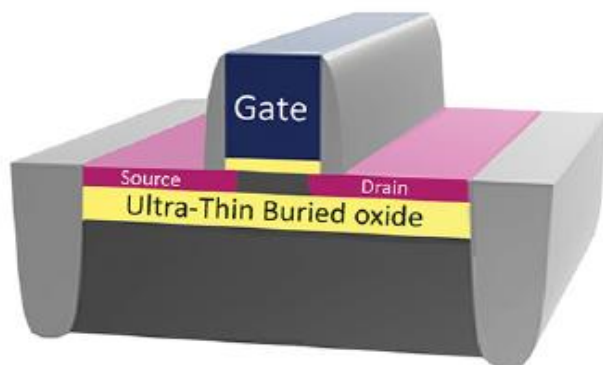
S-parameter measurement



Iso-thermal frequency



Self heating model



Recently published BOOK on BSIM-IMG

- Core Modeling
- I-V & C-V Modeling
- Leakage Current Modeling
- RF and Noise Models in BSIM-IMG

INDUSTRY STANDARD FDSOI COMPACT MODEL BSIM-IMG FOR IC DESIGN

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HARSHIT AGARWAL

Summary

- **Core I-V and C-V models for independent multi-gate FETs are developed and verified with TCAD without using fitting parameters**
- **BSIM-like short channel real device effects are implemented.**
- **Double hump gm behavior analysed and modelled**
- **RF and Noise models in BSIM-IMG are developed**

THANK
YOU!

